TSM Jan 29 TOX

January 22, 2004

To: Commissioner for Patents P.O.Box 1450 Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572 28 Davis Avenue Poughkeepsie, N.Y. 12603

Subject:

Serial No. 10/700,779 11/04/03

An-Chun Tu et al.

METHOD FOR IMPROVING INTERLEVEL DIELECTRIC GAP FILLING OVER SEMI-CONDUCTOR STRUCTURES HAVING HIGH ASPECT RATIOS

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation In An Application.

The following Patents and/or Publications are submitted to comply with the duty of disclosure under CFR 1.97-1.99 and 37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on January 7, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

- U.S. Patent 5,751,040 to Chen et al., "Self-Aligned Source/Drain Mask ROM Memory Cell Using Trench Etched Channel," describes a method for forming vertical FETs for ROM memory cells in which a source is formed in a trench, an FET channel is formed in the trench wall, and a drain on the surface which are self-aligned.
- U.S. Patent 4,994,404 to Sheng et al., "Method for Forming a Lightly-Doped Drain (LDD) Structure in a Semiconductor Device," discusses using a disposable amorphous carbon sidewall spacer to self-align the souce/drain contacts to the LDD.
- U.S. Patent 6,380,535 to Wetzel et al., "Optical Tuft for Flow Separation Detection," describes a method for making sidewall spacers on an FET gate electrode without damaging the substrate during etching.
- U.S. Patent 6,455,373 to Pham et al., "Semiconductor Device Having Gate Edges Protected from Charge Gain/Loss," discusses making flash memory (floating gate) FETs in which the sidewalls are of different thicknesses on the source and drain sides to reduce leakage currents, such as ion charge and the like.

TSMC-03-268

U.S. Patent 6,365,943 to Gardner et al., "High Density Integrated Circuit," describes a method for making two levels of FET devices to increase circuit density on the chip.

Sincere Ty

Stephen B. Ackerman,

Reg. No. 37761

· , `•	•					Jiren	6-f-1
P	FORMATION DISCLOSURE CITATION			15MC-03-26	1	0/700,	779
», [An-Cha	-		- 1
JAN 2	The Fi	IN AN APPLICATION (Usin several showts if necessary)		Fixing Desta	<u> </u>	LOND YLI MALL	ما،
. 1		(029 29491M 2109(2 II 11009227A)	II G' DATE	II/04/03 ENT DOCUMENTS			
WELT &	EXAMINER	DOCUMENT HUMBER DATE	0. 3. FA12	HAME .	CLARS	WS CLAS	ለሁኑ፡፡፡፡ DATE ¥ ኢዮጵያውያመል፤ ር
	MIM		CI				1 /
		5 7510 40 5/2/98	Chen	et al.	257	332	9/16/96
		4994404219191	Shen	g et al.	437	44	8/28/89
		63659434202	Gardn	er et al.	257	377	9/21/98
ļ		63805354/30/02	Wetz	eletal.	250	227.14	8/6/99
	÷	64553739/24/02	Pham	et de	438	257	4/12/01
			l				
				!			_
	FOREIGN PATENT DOCUMENTS						
		OCCUMENT NUMBER CATE	co.	COUNTRY		ะขนวงขนะ	Translation YES NO
							-
			OTUED DOC	UMENTS (Induding Aut	nos Trio O	ele Perior i	Proce Fig.
			OTHER DOC	OMENTS (IICUCIOAU	101, 1100, 0	alo, Foldiolix I	- ayos, cic./
							——————————————————————————————————————
					···		
							
						·····	
				,			
	EXAMMER	· · · · · · · · · · · · · · · · · · ·		DATE CONCIDENED			
ş						,	

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.